

COLUMBIA UNIVERSITY IN THE CITY OF NEW YORK COLUMBIA NANO INITIATIVE / CENTER FOR INTEGRATED SCIENCE AND ENGINEERING

Woollam Ellipsometer Standard Operating Procedure

These instructions are intended for reference only, and will *not* replace the thorough training required for proper system operation. Contact a superuser/staff member with questions or to report a system problem.



Written by Dr. Dan Paley Updated by Dr. Manju Rajeswaran

COLUMBIA | NANO INITIATIVE

COLUMBIA UNIVERSITY

IN THE CITY OF NEW YORK

COLUMBIA NANO INITIATIVE / CENTER FOR INTEGRATED SCIENCE AND ENGINEERING



🖆 Columbia | Nano Initiative

$Columbia \ University$





🖆 Columbia | Nano Initiative

COLUMBIA UNIVERSITY

COLUMBIA NANO INITIATIVE / CENTER FOR INTEGRATED SCIENCE AND ENGINEERING



🖆 Columbia | Nano Initiative

Columbia University



IN THE CITY OF NEW YORK COLUMBIA NANO INITIATIVE / CENTER FOR INTEGRATED SCIENCE AND ENGINEERING

12	Click on Analysis tab, and check the measured Silicon Oxide thickness. The thickness should be 25 nm +/- 10%. If the thickness is outside that range, stop and notify Super User.	Model: 25nm Oxide on Si (25nm Oxide on Si model) Ogen Save Clear Layer Commands: CC Delete Save Include Surface Roughness = <u>OFF</u> Layer # 2 = SIO2_JAW Oxide Thickness = <u>24.53 nm</u> (fit) Layer # 1 = INTR_JAW Interface Thickness = <u>1.00 nm</u> Substrate = <u>SI_JAW</u> Angle Offset = <u>0.0195</u> (fit) + MODEL Options + FIT Options + OTHER Options <u>Configure Options</u> <u>Turn Off All Fit Parameters</u>
13	Write down the Angle Offset.	Model: 25nm Oxide on Si (25nm Oxide on Si model) Ogen Save Layer Commands: Clear Layer Commands: MCC Delete Save Include Surface Roughness = OFF Layer # 2 = SIO2_JAW Variation Substrate = SLJAW Angle Offset = 0.0195 FIT Options + FIT Options + OTHER Options Configure Options Turn Off All Fit Parameters
14	Still in Analysis Tab, click Open under Model. Choose desired Model (most used models are in Basics folder under Library tab). Refer to Complete Ease Manual or contact Super User for model selection if unsure.	Job Set Rages Quer Commands Gold Datas Save Include Surdar Roughness - QFH Layer # 2 = SIO2_LW. Thickness # 2 = 10.00 nm (ft) Image: Commands Gold Datas Save Include Surdar Roughness - QFH Layer # 2 = SIO2_LW. Thickness # 2 = 10.00 nm (ft) Image: Commands Gold Datas Save Image: Commands Layer # 2 = SIO2_LW. Thickness # 2 = 10.00 nm (ft) Image: Commands Data Save Image: Commands Layer # 2 = SIO2_LW. Thickness # 2 = 10.00 nm (ft) Image: Commands Data Save Image: Commands Layer # 2 = SIO2_LW. Thickness # 2 = 10.00 nm (ft) Image: Commands Image: Commands Layer # 2 = SIO2_LW. Thickness # 2 = 10.00 nm (ft) Image: Commands Image: Commands Layer # 2 = SIO2_LW. Thickness # 2 = 10.00 nm (ft) Image: Commands Image: Commands Image: Commands Layer # 2 = SIO2_LW. Thickness # 2 = 10.00 nm (ft) Image: Commands Image: Commands Image: Commands Image: Commands Layer # 2 = SIO2_LW. Thickness # 2 = 10.00 nm (ft) Image: Commands Image: Commands Image: Commands Image: Commands Image: Commands Layer # 2 = SIO2_LW. Thickness # 2 = 10.00 nm (ft)
15	Model selection suggestions:	
	10 nm on wafer: Use "Si with Native Oxide" model. * For oxide thickness more than 10 nm on wafer: Use "Si with Thermal Oxide" model. * For layer with thickness larger than 10nm on wafer: Use either "Si with Transparent Thin Film" or "Si with Absorbing Film"	

Columbia | Nano Initiative

COLUMBIA UNIVERSITY



IN THE CITY OF NEW YORK COLUMBIA NANO INITIATIVE / CENTER FOR INTEGRATED SCIENCE AND ENGINEERING

	model, depending on the transparency of the film.	
16	Enter Angle Offset (if applicable) by clicking on the number of the Angle Offset. Enter value for the Angle Offset then click OK.	Angle Offset = <u>0.00</u> (fit)
17	If no model is available for your sample: You can add, delete and modify individual layers, selecting sub-models for the layers by clicking on their names.	Model: Si with Thermal Oxide Ogen Saye Clear Layer Commands: GC Delete Save Include Surface Roughness PEF Layer # 2 = SIO2_IAW Includess # 2 = 100.00 nm (fit) Layer # 1 = INTR_IAW Includess # 1 = 100 nm Substrate = SI_JAW Includess # 1 = 100 nm Angle Offset = 0.00 (fit) MODEL Options + FIT Options OTHER Options Configure Options Turn Off All Fit Parameters
18	Any thickness or angle offset value with "(fit)" at the end is a refined parameter. To fix any value (a.k.a. don't want to measure this value), right click on the value to remove "(fit)" at the end (or click on the value and uncheck the Fit box). User can also enter desired thickness for each layer by clicking on the value and enter the number wanted.	Include Surface Rougnness = <u>OFF</u> Layer # 2 = <u>SIO2_JAW</u> Thickness # 2 = <u>24,54 nm</u> (fit) Layer # 1 = <u>INTR_JAW</u> Thickness # 1 = <u>1.00 nm</u> Substrate = <u>SI JAW</u> Angle + MODE + FIT OP + OTHEF <u>Conflic</u> Turn C <u>Minimum</u> : <u>1.00</u> Magimum: <u>10000.00</u> <u>V</u> Show Adv. Parameters
19	After choosing model and layer thickness to be measured, click on Measurement tab and click Measure. Notes: The MSE given here can be very high, depending on the condition of the sample's surface or the accuracy of the model. The higher the MSE, the higher the +/- value.	Measurement Analysis Hardware Options System Status Waiting to Acquire Data F Measurement Controls Mgde: Standard Sample Alignment Model: Slample Alignment Standard F Model: Slample Alignment Standard F Model: Slample Alignment Standard Market Model: Slawe Data after Measurement Measure
20	To open old data, first choose the right model and layer thickness in Model window, then click Open in Data Window. Choose the file and click Open. Then click Fit to retrieve the data wanted.	

Columbia University



IN THE CITY OF NEW YORK COLUMBIA NANO INITIATIVE / CENTER FOR INTEGRATED SCIENCE AND ENGINEERING

21	To combine multiple data and find the best fit, first open one data value (see step 20). Then right-click on Open in Data window and choose Append Data. Click on all wanted data files and click Append. Then click Fit to get the best fit from all the data with the chosen model. Click Save to save the data.	Measurement Analysis Hardware Options Data: Data Not Saved Model: Si with Al Ope Append Data Sis Fit Append Intensity Data From Text File Imma Gene C:CompleteEASE:Thu VISI 385/SI 385 Alkyne 4.SE Ifac C:CompleteEASE:Thu VISI 385/SI 385 Alkyne 5.SE E Thick C:CompleteEASE:Thu VISI 385/SI 385 Alkyne 3.SE Et = C:CompleteEASE:Thu VISI 385/SI 385 PS 3.SE Ptic C:CompleteEASE:Thu VISI 385/SI 385 PS 4.SE Ptic C:CompleteEASE
22	Click "Graph Type" in Graph window to see plot of different measurement value.	Graph Type Psi Ctrl-P Delta Ctrl-D Re(rho) Im(rho) M Ctrl-C S Ctrl-S <psgudo>Transforms Intensity Ctrl-T Depolarization Ctrl-Z M Double Y Avis Difference Mode More Options</psgudo>
23	Once done, turn off instrument and close Complete Ease. Fill out log book.	
24	Disable the instrument on BADGER.	Image: Constraint of the second se

Columbia | Nano Initiative